L Number	Hits	Search Text	DB	Tim stamp
21	116	(acc leration near s ns r) and 257/415	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 09:40
22	28	(acceleration near sensor).clm. and 257/415	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 09:40
-	21157	acceleration adj sensor	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:12
-	2028	(acceleration adj sensor).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:12
-	177	(acceleration adj sensor).clm. and beam.clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:12
-	5	(acceleration adj sensor).clm. and beam.clm. and (piezoresistor).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:13
-	0	(acceleration adj sensor).clm. and beam.clm. and (piezoresistor).clm. and (tft or (thin near film near transistor)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:13
-	0	(acceleration adj sensor).clm. and (piezoresistor).clm. and (tft or (thin near film near transistor)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:13
-	0	(acceleration adj sensor).clm. and (tft or (thin near film near transistor)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:16
-	1	(acceleration adj sensor).clm. and (tft or (thin near film near transistor))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:17

-	26	(ac l rati n adj sensor) and (tft or (thin n ar film near transist r))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:17
-	3	(acceleration adj sensor) and (tft or (thin near film near transistor)) and (piezo or piezoresistor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:17
-	165494	sensor.clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:17
-	259	sensor.clm. and (tft or (thin near film near transistor)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:18
-	0	sensor.clm. and (tft or (thin near film near transistor)).clm. and piezoresistor.clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:19
-	0	(acceleration near sensor).clm. and (tft or (thin near film near transistor)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:20
-	6870	(tft or (thin near film near transistor)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:20
-	259	(tft or (thin near film near transistor)).clm. and sensor.clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:21
-	26	(tft or (thin near film near transistor)).clm. and sensor.clm. and beam.clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:21
-	15	(tft or (thin near film near transistor)).clm. and sensor.clm. and beam.clm. and sensor.ab.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:22

-	9	(tft or (thin n ar film n ar transist r)).clm. and sens r.clm. and beam.clm. and s ns r.ab. and substrat .clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:22
-	9	(tft or (thin near film near transistor)).clm. and sensor.clm. and beam.clm. and sensor.ab. and substrate.clm. and (tft or (thin near film near transistor)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:22
-	0	(tft or (thin near film near transistor)).clm. and sensor.clm. and beam.clm. and sensor.ab. and substrate.clm. and (tft or (thin near film near transistor)).ab.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:22
-	0	(tft or (thin near film near transistor)).clm. and sensor.clm. and beam.clm. and sensor.ab. and substrate.clm. and (piezo or piezoelectric or piezoresistor)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:23
-	0	(tft or (thin near film near transistor)).clm. and sensor.clm. and beam.clm. and sensor.ab. and substrate.clm. and (piezo or piezoelectric or piezoresistor).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:23
-	1	(tft or (thin near film near transistor)).clm. and sensor.clm. and sensor.ab. and substrate.clm. and (piezo or piezoelectric or piezoresistor).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:23
-	2099	(acceleration near sensor).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:24
-	0	(acceleration near sensor).clm. and (tft or (thin near film near transistor)).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:24
-	1	(acceleration near sensor).clm. and (tft or (thin near film near transistor))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:24
-	201	(acceleration near sensor).clm. and (piezo or piezoelectric or piezoresistor).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:24

-	201	(acc leration n ar s ns r).clm. and (piez or piez electric r piezoresistor).clm.	USPAT; U -PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:27
-	31	(acceleration near sensor).clm. and (piezo or piezoelectric or piezoresistor).clm. and (cantilever or beam).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:28
-	4	(acceleration near sensor).clm. and (piezo or piezoelectric or piezoresistor).clm. and (cantilever or beam).clm. and (thin near film)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:28
-	4	(acceleration near sensor).clm. and (piezo or piezoelectric or piezoresistor).clm. and (cantilever or beam).clm. and ((thin near film) or tft)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:28
-	1	(acceleration near sensor).clm. and (piezo or piezoelectric or piezoresistor).clm. and (cantilever or beam).clm. and ((thin near film) or tft).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:29
-	0	(acceleration near sensor).clm. and (piezo or piezoelectric or piezoresistor).clm. and (cantilever or beam).clm. and (tft).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:29
-	0	(acceleration near sensor).clm. and (piezo or piezoelectric or piezoresistor).clm. and (cantilever or beam).clm. and (tft)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:29
-	4	(sensor).clm. and (piezo or piezoelectric or piezoresistor).clm. and (cantilever or beam).clm. and (tft)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:32
-	2099	(acceleration near sensor).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:32
-	56	(acceleration near sensor).clm. and (insulating or dielectric).clm. and substrate.clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:33

-	0	(accelerati n near sensor).clm. and (insulating or dielectric).clm. and substrate.clm. and tft	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:33
-	23	(acceleration near sensor).clm. and (insulating or dielectric).clm. and substrate.clm. and (tft or (thin near film))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:33
-	0	(acceleration near sensor).clm. and (insulating or dielectric).clm. and substrate.clm. and (tft or (thin near film near transistor))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:34
-	4380	(insulating or dielectric).clm. and substrate.clm. and (cantilever or beam).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:35
-	3	(insulating or dielectric).clm. and substrate.clm. and (cantilever or beam).clm. and piezoresistor.clm.\	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:35
-	3	(insulating or dielectric).clm. and substrate.clm. and (cantilever or beam).clm. and piezoresistor.clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:35
-	0	(insulating or dielectric).clm. and substrate.clm. and (cantilever or beam).clm. and piezoresistor.clm. and (acceleration near sensor).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:35
-	0	(insulating or dielectric).clm. and substrate.clm. and (cantilever or beam).clm. and (piezo or piezoelectric or piezoresistor).clm. and (acceleration near sensor).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:36
-	31	(cantilever or beam).clm. and (piezo or piezoelectric or piezoresistor).clm. and (acceleration near sensor).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:36
-	21	(cantilever or beam).clm. and (piezo or piezoelectric or piezoresistor).clm. and (acceleration near sensor).clm. and (acceleration near sensor).ab.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:39

-	13	(cantilev r r beam).clm. and (piezo r piezoel ctric r pi zoresistor).clm. and (acceleration near sens r).clm. and (acceleration near sensor).ab. and beam.clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:39
-	6	(cantilever or beam).clm. and (piezo or piezoelectric or piezoresistor).clm. and (acceleration near sensor).clm. and (acceleration near sensor).ab. and beam.clm. and substrate.clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:40
-	0	(cantilever or beam).clm. and (piezo or piezoelectric or piezoresistor).clm. and (acceleration near sensor).clm. and (acceleration near sensor).ab. and beam.clm. and substrate.clm. and (insulating or dielectric).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:40
-	1	(cantilever or beam).clm. and (piezo or piezoelectric or piezoresistor).clm. and (acceleration near sensor).clm. and (acceleration near sensor).ab. and beam.clm. and substrate.clm. and (thin near film).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:42
-	0	(cantilever or beam).clm. and (piezo or piezoelectric or piezoresistor).clm. and (acceleration near sensor).clm. and (acceleration near sensor).ab. and beam.clm. and substrate.clm. and (thin near film).clm. and (pcb or printed).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:42
-	0	(cantilever or beam).clm. and (piezo or piezoelectric or piezoresistor).clm. and (acceleration near sensor).clm. and (acceleration near sensor).ab. and beam.clm. and substrate.clm. and (pcb or printed).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:42
-	6	(cantilever or beam).clm. and (piezo or piezoelectric or piezoresistor).clm. and (acceleration near sensor).clm. and (acceleration near sensor).ab. and beam.clm. and substrate.clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:42
-	4	(cantilever or beam).clm. and (piezo or piezoelectric or piezoresistor).clm. and (acceleration near sensor).clm. and (acceleration near sensor).ab. and beam.clm. and substrate.clm. and (cantilever or cantilevered).clm.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:43
-	4	(cantilever or beam).clm. and (piezo or piezoelectric or piezoresistor).clm. and (acceleration near sensor).clm. and (acceleration near sensor).ab. and beam.clm. and substrate.clm. and (cantilever or cantilevered).clm. and (cantil v r r cantilever d).ab.	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/06 11:45